

2851

00862.022246

PATENT APPLICATION

APR 30 2003

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Kazunori IWAMOTO et al.

Application No.: 09/866,600

Filed: May 30, 2001

For: STAGE APPARATUS WHICH SUPPORTS INTERFEROMETER,  
STAGE POSITION MEASUREMENT METHOD, PROJECTION  
EXPOSURE APPARATUS, PROJECTION EXPOSURE  
MAINTENANCE METHOD, SEMICONDUCTOR DEVICE  
MANUFACTURING METHOD, AND SEMICONDUCTOR  
MANUFACTURING FACTORY

)  
: Examiner: H. Nguyen  
)  
: Group Art Unit: 2851  
)  
:  
)  
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)

April 30, 2003

Commissioner for Patents  
Washington, D.C. 20231

Sir:

Transmitted herewith is an Amendment in the above-identified application.

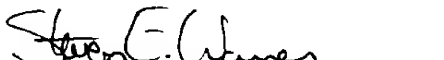
☒ No additional fee is required.

The fee has been calculated as shown below:

CLAIMS AS AMENDED						
	CLAIMS REMAINING AFTER AMENDMENT		HIGHEST NO. PREVIOUSLY PAID FOR	PRESENT EXTRA	RATE	ADDITIONAL FEE
TOTAL CLAIMS	30	MINUS	30	= 0	x \$9 \$18	\$0.00
INDEP. CLAIMS	5	MINUS	5	= 0	x \$42 \$84	\$0.00
Fee for Multiple Dependent claims \$140/\$280						—
TOTAL ADDITIONAL FEE FOR THIS AMENDMENT						\$0.00

- ☐ °Verified Statement claiming small entity status is enclosed, if not filed previously.
- ☐ A check in the amount of \$\_\_\_\_\_ is enclosed including the additional claims fees.
- ☐ Charge \$\_\_\_\_ to Deposit Account No. 06-1205. A duplicate of this sheet is enclosed.
- ☒ Any prior general authorization to charge an issue fee under 37 CFR 1.18 to Deposit Account No. 06-1205 is hereby revoked. The Commissioner is hereby authorized to charge any additional fees under 37 CFR 1.16 and 1.17 which may be required during the entire pendency of this application, or to credit any overpayment, to Deposit Account No. 06-1205. A duplicate of this paper is enclosed.
- ☐ A check in the amount of \$\_\_\_\_\_ to cover the fee for a two month extension is enclosed.
- ☐ A check in the amount of \$\_\_\_\_\_ to cover the Information Disclosure Statement fee is enclosed.
- ☒ Applicants' undersigned attorney may be reached in our Washington, D.C. office by telephone at (202) 530-1010. All correspondence should be directed to our address given below.

Respectfully submitted,

  
Attorney for Applicants  
Steven E. Warner  
Registration No. 33,326

FITZPATRICK, CELLA, HARPER & SCINTO  
30 Rockefeller Plaza  
New York, New York 10112-3801  
Facsimile: (212) 218-2200  
SEW/eab  
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# 7 drawings  
K. Duncan  
5/6/03

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EXPOSURE APPARATUS MAINTENANCE  
METHOD, SEMICONDUCTOR DEVICE  
MANUFACTURING METHOD, AND  
SEMICONDUCTOR MANUFACTURING FACTORY :

Examiner: H. Nguyen

Group Art Unit: 2851

April 30, 2003

Commissioner for Patents  
Washington, D.C. 20231

REQUEST FOR APPROVAL OF DRAWING CHANGES

Sir:

Applicants request that the Examiner approve the changes to Figures 5 and 6, as shown in red on the attached sketches, enclosed in duplicate.

In Figure 5, under "FIG. 5," insert -- PRIOR ART --, as shown.

In Figure 6, under "FIG. 6," insert -- PRIOR ART --, as shown.

Favorable consideration is requested.

Approved  
10/1/03  
HN

Applicants' undersigned attorney may be reached in our Washington, D.C. office by telephone at (202) 530-1010 All correspondence should continue to be directed to our address given below.

Respectfully submitted,

A handwritten signature in dark ink, appearing to read "Steven E. Warner", is written over a horizontal line.

Attorney for Applicants

Steven E. Warner

Registration No. 33,326

FITZPATRICK, CELLA, HARPER & SCINTO  
30 Rockefeller Plaza  
New York, New York 10112-3801  
Facsimile: (212) 218-2200  
SEW/eab

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